

Attorney Docket: 061063-0356139
Client Reference: OSP-19398

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:
HOURAI, ET AL.

Confirmation Number: 2722

Application No.: ***10/587,039***

Group Art Unit: 1722

Filed: July 24, 2006

Examiner: HITESHEW, Felisa C.

Title: SILICON WAFER, METHOD FOR MANUFACTURING THE SAME AND METHOD
FOR GROWING SILICON SINGLE CRYSTALS

AMENDMENT UNDER 37 C.F.R. § 1.111

Mail Stop Non-Fee Amendments

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed August 22, 2007, the date for responding being
November 22, 2007, please amend the above-identified application as follows: